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## Information Disclosure Citation Listing

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**INFORMATION DISCLOSURE CITATION**

(Use several sheets if necessary)

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Applicant: Joachim MAI, et al.

Filing Date:

Group:

**U.S. PATENT DOCUMENTS**

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
		US-					

**FOREIGN PATENT DOCUMENTS**

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	F1	DE- 4108404	10/10/1991	DE				N*
	F2	DE- 39724	1/23/1964	DE				N <sup>P</sup>

TRANSLATION KEY: \* English Abstract. <sup>F</sup> Concise statement of relevance provided in foreign search report. <sup>C</sup> Concise statement of relevance provided in specification or in attachment to document. <sup>S</sup> Concise statement of relevance provided in IDS. <sup>P</sup> Relevant portion of document translated. <sup>O</sup> English abstract only - copy of document in pct search.

**OTHER INFORMATION DISCLOSURE CITATIONS (Including Author, Title, Date, Pertinent Pages, Etc.)**

	01	5/21/2003 "Reactive etching of semiconductor surfaces using an electronically chopped low energy broad beam ion source" J. Dienelt et al. Elsevier Science B.V., Surface and Coatings Technology Volumes 174-175 Pages 157-161
	02	7/17/2003 "Generation of a pulsed ion beam with a tuned electronic beam switch" J. Dienelt et al. Plasma Sources Science and Technology Vol. 12 Pages 489-494

**EXAMINER****DATE CONSIDERED**

**EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.